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(71) Applicant: NIPPON SODA CO LTD

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(54) TRANSPARENT ELECTROCONDUCTIVE FILM-ATTACHED GLASS HAVING HIGH RESISTANCE

(57) Abstract:

PURPOSE: To obtain transparent electroconductive film-attached glass having high resistance and excellent in uniformity by forming a film of silicon dioxide onto a glass substrate and forming a transparent electroconductive film thereon to provide a film having two layer

structure.

and \pm 2% linearity value is formed in a silicon dioxide is formed into a film by n an amount of 0.01-10wt.% based on a sputtering method, a CVD method, a transparent electroconductive film and transparent glass substrate in a film thickness of 60-150nm. A transparent electroconductive film having 1.7-2.2 amount of 0.01-10wt.% and/or boron film thickness of 10-30nm thereon to electroconductive filmattached glass. refractive index, $200-3000\Omega$ /square ITO, FTO, ATO, etc., is used as the CONSTITUTION: Silicon dioxide film containing phosphorus in an provide the objective transparent silicon dioxide is formed on a spraying method, etc.

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